

Applicant: Eun-Taek Kim, et al.
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Title: METHOD FOR CLEANING A DEPOSITION CHAMBER AND DEPOSITION
APPARATUS FOR PERFORMING IN SITU CLEANING

INFORMATION DISCLOSURE CITATION
FORM PTO-1449 (Modified)

FOREIGN PATENT DOCUMENTS

| <u>Exam</u> <u>Init</u> | <u>Ref</u> | <u>Document</u> <u>Number</u> | <u>Publication</u> <u>Date</u> | <u>Country</u> | <u>Name</u> |
|----------------------------|------------|----------------------------------|-----------------------------------|----------------|------------------|
| _____ | _____ | JP11222679 | 8/17/1999 | Japan | Toshiyuki et al. |

OTHER DOCUMENTS

| <u>Exam</u> <u>Init</u> | <u>Ref</u> | <u>Author, Title, Date, Pertinent Pages, Etc.)</u> |
|----------------------------|------------|--|
| _____ | _____ | English language Abstract from Japanese Patent Publication No. JP11222679 published 8/17/1999. |

Examiner: _____

Date Considered: _____